Michael G. Monroe et al.

Herewith

the date indicated above and is addressed to: Commissioner for Patents, Alexandria, VA

for

Typed Name: John A. Parker

22313-1450.

Patents,

Alexandria,

Inv nt r(s):

Filing Date:

Application No.:

PATENT APPLICATION

ATTORNEY DOCKET NO. _ 200309716-1

Confirmati n N .:

Group Art Unit: Unkn.

Examiner:

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Title:	MEMS DEVICE AND METHOD OF FORMING MEMS DEVICE				
PO Box 145	ner for Patents 50 VA 22313-1450 INFORMATION DISCLOSURI	F STATEMENT			
Sir:					
This Info	ormation Disclosure Statement is submitted:				
(x)	under 37 CFR 1.97(b), or (Within three months of filing national application; or mailing date of first office action on the merits; whichev	date of entry of national application; or before er occurs last)			
	under 37 CFR 1.97(c) together with either a: () Statement under 37 CFR 1.97(e), or () a \$180.00 fee under 37 CFR 1.17(p), or (After the CFR 1.97 (b) time period, but before final acti under 37 CFR 1.97 (d) together with a: () Statement under 37 CFR 1.97(e)(1) or (2 () a \$180.00 fee set forth in 37 CFR 1.17(p) (Filed after final action, a notice of allowance, on or), and b).			
pendency of	charge to Deposit Account 08-2025 the sur of this application, please charge any fees re 3-2025 pursuant to 37 CFR 1.25.	m of <u>\$0.00</u> . At any time during the equired or credit any overpayment to Deposit			
any required applicant(s)	d copies of patents, publications or other info	nformation Disclosure Statement together with rmation of which applicant(s) are aware, which of this application and for which there may be			
and other individuals(sattached shoreign patereport or ac	foreign language information listed on PTO s) designated in 37 CFR 1.56 (c) most know neet, or where a foreign language patent is ent office in a counterpart foreign applicatio	anguage patents, foreign language publications Form 1449, as presently understood by the reledgeable about the content is given on the cited in a search report or other action by a in, an English language version of the search ound by the foreign office is listed on form PTO			
It is request	ed that the information disclosed herein be ma	ade of record in this application.			
"Express Mail"	label no. EV310988162US	Respectfully submitted,			
	of Deposit Oct. 2, 2003	Michael G. Monroe et al.			
I hereby certify United States Office to Addr	y that this is being deposited with the Postal Service "Express Mail Post essee" service under 37 CFR 1.10 on	By			

Rev 10/03 (IDSXML) Telephone No.: (612) 573-2006

Scott A. Lund

Reg. No.

Attorney/Agent for Applicant(s)

41,166

Date: Oct. 2, 2003

PATENT APPLICATION

Sheet 1 of 2

FORM PTO 1440					ATTY. DOCKET NO. 200309716-1	APPLICATION NO. CONFIRMA	TION NO	
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE APPLICANT'S INFORMATION DISCLOSURE								
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STATEMENT					FILING DATE	GROUP		
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REFERE	NCE	DESIGNATION	U.S. P	ATEN	T DOCUMENTS			
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PATENT APPLICATION

Sheet 2 of 2

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	2J			+			<u></u>
	2K			+			
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Rev 05/03 (PTO1449)